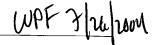
09/970,100

Number	14:44 14:44 14:48 14:48 14:49 14:49 12:33
12 (((silica silicon) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) (("3860400") or ("4047902") or ("4078906") or ("4256467") or ("4288233") or ("4826508") or ("4874478")).PN. ((ceria "Ceo2") with abrasive) same (vapor adj deposition) same bind\$3 same (back\$3 support\$3 substrate) (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((titania "Ti02") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "Zro2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "Zro2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] MEIKLE-Scott-G[in] M	14:44 14:44 14:48 14:48 14:49 14:49 12:33
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Support\$3 substrate) (("3860400") or ("4047902") or ("4078906") or ("4256467") or ("4288233") or ("4826508") or ("4874478")).PN. ((ceria "CeO2") with abrasive) same (vapor adj deposition) same bind\$3 same (back\$3 support\$3 substrate) 2 (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 39 ((titania "TiO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 40 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] ((427/430.1) or (427/419.1)).CCLS. ((427/430.1) or (427/419.1)).CCLS. 2003/10/23 1	14:48 14:48 14:49 14:49 12:33
7 (("3860400") or ("4047902") or ("4078906") or ("4256467") or ("4288233") or ("4826508") or ("4874478")).PN. ((ceria "CeO2") with abrasive) same (vapor adj deposition) same bind\$3 same (back\$3 support\$3 substrate) 2 (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((titania "TiO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] EPO; JPO; DERWENT ((AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. ((51/295) or (51/309)).CCLS. USPAT; 2003/10/23 1 EPO; JPO; DERWENT USPAT; 2003/10/23 1	14:48 14:48 14:49 14:49 12:33
or ("4256467") or ("428233") or ("4826508") or ("487478")).PN. 0 ((ceria "Ceo2") with abrasive) same (vapor adj deposition) same bind\$3 same (back\$3 support\$3 substrate) 2 (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 39 ((titania "Tio2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 63 ((zirconia "Zro2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] EPO; JPO; DERWENT 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) 2135 ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. ((51/295) or (51/309)).CCLS. DERWENT 2004/07/26 1 200	14:48 14:48 14:49 14:49 12:33
or ("4256467") or ("428233") or ("4826508") or ("487478")).PN. 0 ((ceria "Ceo2") with abrasive) same (vapor adj deposition) same bind\$3 same (back\$3 support\$3 substrate) 2 (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 39 ((titania "Tio2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 63 ((zirconia "Zro2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] EPO; JPO; DERWENT 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) 2135 ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. ((51/295) or (51/309)).CCLS. DERWENT 2004/07/26 1 200	14:48 14:48 14:49 14:49 12:33
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adj deposition) same bind\$3 same (back\$3 support\$3 substrate) (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((titania "TiO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. ((51/295) or (51/309)).CCLS. 3538 ((51/295) or (51/309)).CCLS. USPAT: EPO; JPO; DERWENT USPAT: EPO; JPO; DERWENT USPAT: EPO; JPO; DERWENT 2003/10/23 1	4:48 4:49 4:49 2:33 5:36
Support\$3 substrate)	4:49 4:49 2:33 5:36
2 (((titanic titanium) adj nitride) with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 39 ((titania "TiO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) 2135 ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. 3538 ((51/295) or (51/309)).CCLS. 2004/07/26 1	4:49 4:49 2:33 5:36
abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((titania "TiO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] ((AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT 2135 ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. 3538 ((51/295) or (51/309)).CCLS.	4:49 4:49 2:33 5:36
Support\$3 substrate) ((titania "Ti02") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "Zr02") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98	.4:49 .2:33 .5:36
39 ((titania "Ti02") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) ((zirconia "Zr02") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98	.4:49 .2:33 .5:36
bind\$3 same (back\$3 support\$3 substrate) ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 3538 ((51/295) or (51/309)).CCLS. USPAT; EPO; JPO; DERWENT	.4:49 .2:33 .5:36
63 ((zirconia "ZrO2") with abrasive) same bind\$3 same (back\$3 support\$3 substrate) 98 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) 2135 ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 3538 ((51/295) or (51/309)).CCLS. USPAT; EPO; JPO; DERWENT USPAT; EPO; JP	.2:33
bind\$3 same (back\$3 support\$3 substrate) AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. 3538 ((51/295) or (51/309)).CCLS. DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT EPO; JPO; DERWENT EPO; JPO; DERWENT	.2:33
98 AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in] 71 (AGARWAL-Vishnu-K[in] AGARWAL-Vishnu[in] MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 2818 ((51/295) or (51/309)).CCLS. 3538 ((51/295) or (51/309)).CCLS. 2003/02/03 1 EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT EPO; JPO; DERWENT	.5:36
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MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (polish polishing planarize planarization backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 3538 ((51/295) or (51/309)).CCLS. MEIKLE-Scott-G[in] MEIKLE-Scott[in]) and (EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT EPO; JPO; DERWENT	
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backing "contour surfaces" nodule) ((427/430.1) or (427/419.1)).CCLS. 2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 3538 ((51/295) or (51/309)).CCLS. USPAT; EPO; JPO; DERWENT	3:44
2135 ((427/430.1) or (427/419.1)).CCLS. USPAT; EPO; JPO; DERWENT USPAT; (427/203)).CCLS. EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT	3:44
2818 ((427/430.1) or (427/419.1) or USPAT; (427/203)).CCLS. EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT	3:44
2818 ((427/430.1) or (427/419.1) or (427/203)).CCLS. 3538 ((51/295) or (51/309)).CCLS. EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT	
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(427/203)).CCLS. EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT	j
(427/203)).CCLS. EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT USPAT; EPO; JPO; DERWENT	3:44
3538 ((51/295) or (51/309)).CCLS. USPAT; 2003/10/23 1 EPO; JPO; DERWENT	
EPO; JPO; DERWENT	
EPO; JPO; DERWENT	3:44
DERWENT	
	2.38
EPO; JPO;	2.30
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115 (438/959).CCLS. USPAT; 2003/10/23 1	3.11
EPO; JPO;	3.44
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17 (((427/430.1) or (427/419.1) or USPAT; 2003/10/23 1	2 46
2003/10/23 1	3:46
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(451/526)).CCLS.) ((438/959).CCLS.)) 2864 ((427/430.1) or (427/419.1) or USPAT: 2003/06/17.1	
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(427/203)).CCLS. EPO; JPO;	
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3581 ((51/295) or (51/309)).CCLS. USPAT; 2003/06/17 1	5:10
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121 (438/959).CCLS. USPAT; 2003/06/17 1	5:10
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174 ((((427/430.1) or (427/419.1) or USPAT; 2003/06/17 1	5:12
(427/203)).CCLS.) (((51/295) or EPO; JPO;	
(51/309)).CCLS.) (((451/28) or DERWENT	l
(451/526)).CCLS.) ((438/959).CCLS.)) and	
((back\$3 support) with polymeric) and	[
(abrasive grit)	l
73 ((((427/430.1) or (427/419.1) or USPAT; 2003/06/17 1	5.10
(427/203)).CCLS.) (((51/295) or EPO; JPO;):IZ
1 (54 (000)) 1 (44454 (00)	
(51/309)).CCLS.) (((451/28) or DERWENT (451/526)).CCLS.) ((438/959).CCLS.)) and	
((back\$3 support) with polymeric) and	
((back\$3 support) with polymeric) and (grit)	}
(Arré)	



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		(427/203)).CCLS.) (((51/295) or	EPO; JPO;	
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.)) and		
		((back\$3 support) with polymeric) and		
		(abrasive)		
-	786	compressible near3 (polymer polymeric)	USPAT;	2003/06/17 16:31
			EPO; JPO;	
			DERWENT	
-	41	(USPAT;	2003/06/17 16:31
		and abrasive	EPO; JPO;	
			DERWENT	
-	7	1 (compared nears (porymer porymeric)	USPAT;	2003/06/18 10:19
	ì	same (back\$3 support)) and abrasive	EPO; JPO;	
1	2		DERWENT	
_		(terror	USPAT;	2003/06/18 13:32
		polymeric)) same (back\$3 support)) and	EPO; JPO;	
1_	1	abrasive ("5551959").PN.	DERWENT	
		("3331939").PN.	USPAT	2003/06/18 13:32
	2200	((427/430.1) or (427/419.1)).CCLS.	USPAT;	2003/10/23 13:44
			EPO; JPO;	
_	2984	((427/430.1) or (427/419.1) or	DERWENT	2002/10/02 12
	2504	(427/430.1) of (427/419.1) of (427/203)).CCLS.	USPAT;	2003/10/23 13:44
	[(12//200//.ССБЭ.	EPO; JPO;	
_	3684	((51/295) or (51/309)).CCLS.	DERWENT	0000 (10 (00 10 11
] 3001	((31/293) OI (31/309)).CCLS.	USPAT;	2003/10/23 13:44
			EPO; JPO;	
_	1524	((451/28) or (451/526)).CCLS.	DERWENT	2002/10/22 12 44
	1021	((131/20) OI (431/320/).CCL3.	USPAT; EPO; JPO;	2003/10/23 13:44
			DERWENT	
_	123	(438/959).CCLS.	USPAT;	2003/10/23 13:45
		(100/303/10000	EPO; JPO;	2003/10/23 13:45
			DERWENT	
_	18	(((427/430.1) or (427/419.1) or	USPAT;	2003/10/23 13:45
		(427/203)).CCLS.) and ((((51/295) or	EPO; JPO;	2003/10/23 13:43
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.))	DBIWBINI	
-	8238	(((427/430.1) or (427/419.1) or	USPAT;	2003/10/23 13:46
		(427/203)).CCLS.) or (((51/295) or	EPO; JPO;	2000, 10, 20 13.10
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.))		1
-	0	((((427/430.1) or (427/419.1) or	USPAT;	2003/10/23 13:47
		(427/203)).CCLS.) or ((((51/295) or	EPO; JPO;	
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.))) and		
	!	(polish\$3 abrasive) and (partcile same	1	
	2012	hard)		
-	3219	((((427/430.1) or (427/419.1) or	USPAT;	2003/10/23 13:47
		(427/203)).CCLS.) or ((((51/295) or	EPO; JPO;	
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.))) and (polish\$3 abrasive)		
_	114	((((427/430.1) or (427/419.1) or	HCDAM	2002/10/02 12 12
	114	(427/430.1) or $(427/419.1)$ or $(427/203)$ or $(((51/295))$ or	USPAT;	2003/10/23 13:48
		(51/309)).CCLS.) (((451/28) or	EPO; JPO; DERWENT	
]		(451/526)).CCLS.) ((438/959).CCLS.))) and	DEKWENI	
		(polish\$3 abrasive) and (over\$1coat\$3)		
-	30	((((427/430.1) or (427/419.1) or	USPAT;	2003/10/23 13:51
1		(427/203)).CCLS.) or ((((51/295) or	EPO; JPO;	2003/10/23 13:31
		(51/309)).CCLS.) (((451/28) or	DERWENT	
		(451/526)).CCLS.) ((438/959).CCLS.))) and		
		(polish\$3 abrasive) and (over\$1coat\$3 same		
] [(inorganic hard diamond))		
-	203	(polish\$3 adj pad) and (back\$3 same	USPAT;	2003/10/23 13:54
]		compress\$4)	EPO; JPO;	
	İ		DERWENT	
	16	(polish\$3 adj pad) and (back\$3 same	USPAT;	2003/10/23 13:54
		in\$1compress\$4)	EPO; JPO;	
L			DERWENT	

-	73	(polish\$3 adj pad) and (back\$3 same compressible)	USPAT; EPO; JPO;	2004/07/21 16:03
-	16	(polish\$3 adj pad) and (back\$3 same in\$1compressible)	DERWENT USPAT; EPO; JPO;	2003/10/23 13:58
_	88	(polish\$3 adj pad) and (backing same \$3compress\$4 same pad)	DERWENT USPAT; EPO; JPO;	2004/07/21 16:03
_	83	((polish\$3 adj pad) and (backing same \$3compress\$4 same pad)) not ((polish\$3 adj	DERWENT USPAT; EPO; JPO;	2003/10/23 15:02
_	10	<pre>pad) and (back\$3 same in\$1compressible)) "5551959"</pre>	DERWENT USPAT; EPO; JPO;	2003/10/23 15:51
_	2	5551959[pn]	DERWENT USPAT; EPO; JPO;	2003/10/23 15:51
-	2	("5551959").PN.	DERWENT USPAT; EPO; JPO;	2004/04/14 11:13
_	5	(("5551959") or ("6069080")).PN.	DERWENT USPAT; EPO; JPO;	2004/07/21 12:55
_	9009	((427/430.1) or (427/419.1) or (427/203) or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.	DERWENT USPAT; US-PGPUB;	2004/07/21 12:39
_	1927	(((427/430.1) or (427/419.1) or (427/203)	EPO; JPO; DERWENT; IBM_TDB USPAT;	2004/07/21 12:40
		or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.) and ((polish\$3 near3 pad) abrasive planariz\$4) and (silica ceria alumina titania titanium zirconia ceramic (silic\$3 near3 nitride) (titanium near3 nitride))	EPO; JPO; DERWENT	
-	855	(((427/430.1) or (427/419.1) or (427/203) or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.) and ((polish\$3 near3 pad) abrasive planariz\$4) and ((silica ceria alumina titania titanium zirconia ceramic (silic\$3 near3 nitride) (titanium near3 nitride)) same (coat\$3))	USPAT; EPO; JPO; DERWENT	2004/07/21 12:41
-	39	(((427/430.1) or (427/419.1) or (427/203) or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.) and ((polish\$3 near3 pad) abrasive planariz\$4) and ((silica ceria alumina titania titanium zirconia ceramic (silic\$3 near3 nitride) (titanium near3 nitride)) same	USPAT; EPO; JPO; DERWENT	2004/07/21 12:41
_	40	((top\$1coat\$3) (over\$1coat\$3))) (((427/430.1) or (427/419.1) or (427/203) or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.) and ((polish\$3 near3 pad) abrasive planariz\$4) and ((silica ceria alumina titania titanium zirconia ceramic (silic\$3 near3 nitride) (titanium near3 nitride)) same ((top\$1coat\$3) (over\$1coat\$3)	USPAT; EPO; JPO; DERWENT	2004/07/21 12:42
-	42	(size\$1coat\$3)) (((427/430.1) or (427/419.1) or (427/203) or (51/295) or (51/309) or (451/28) or (451/526) or (438/959)).CCLS.) and ((polish\$3 near3 pad) abrasive planariz\$4) and ((silica ceria alumina titania titanium zirconia ceramic (silic\$3 near3 nitride) (titanium near3 nitride)) same ((top\$1coat\$3) (over\$1coat\$3) (size\$1coat\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/07/21 12:42

-	4	(TIIOTICOUCTS Bupolitically Counce	USPAT;	2004/07/21 12:57
		(((silica silicon) near3 nitride) ceria	EPO; JPO;	
		silica alumina ((titanic titanium) near3	DERWENT	
		nitride) titania titanium zirconia nitride	221112111	
		ceramic)		
1_	139			1
-	139	'	USPAT;	2004/07/21 12:58
		(over\$1coat\$3 same abrasive)) same	EPO; JPO;	
		(((silica silicon) near3 nitride) ceria	DERWENT	
		silica alumina ((titanic titanium) near3		
		nitride) titania titanium zirconia nitride		
	1	ceramic)) not ((size\$1coat\$3		
		<pre>super\$1size\$1coat\$3) same (((silica</pre>		1
	1	silicon) near3 nitride) ceria silica		İ
ĺ		alumina ((titanic titanium) near3 nitride)		
		titania titanium zirconia nitride		
	1	ceramic))	i	
_	13/	(((size\$1coat\$3 super\$1size\$1coat\$3	11055 m	0004/07/04
	134		USPAT;	2004/07/21 14:16
		(over\$1coat\$3 same abrasive)) same	EPO; JPO;	
		(((silica silicon) near3 nitride) ceria	DERWENT	
		silica alumina ((titanic titanium) near3		
		nitride) titania titanium zirconia nitride		ļ
		ceramic)) not ((size\$1coat\$3		
		super\$1cize\$1coa+\$2\ ///		
		super\$1size\$1coat\$3) same (((silica		
		silicon) near3 nitride) ceria silica		
		alumina ((titanic titanium) near3 nitride)		i
1		titania titanium zirconia nitride		
1		ceramic))) not (abrasion\$1resist\$3)		1
_	2		USPAT	2004/07/21 14:40
1 -	11	3508890.URPN.		
I _	6		USPAT	2004/07/21 14:39
1	6	(("1955572") or ("2367286") or ("2427565")	USPAT	2004/07/21 14:40
1		or ("2906612") or ("3310390") or		
		("3351543")).PN.		
-	143	(size\$1coat\$3 super\$1size\$1coat\$3	USPAT;	2004/07/24 16:01
1		(over\$1coat\$3 same abrasive)) same	EPO; JPO;	2001/01/24 10:01
		(((silica silicon) near3 nitride) ceria		
		(((Silica Silicon) heals hittide) certa	DERWENT	
		silica alumina ((titanic titanium) near3		
		nitride) titania titanium zirconia nitride		
		ceramic)		
–	3	(size\$1coat\$3 super\$1size\$1coat\$3) same	USPAT;	2004/07/24 16:35
		((silica adj nitride) (silicon adj	US-PGPUB;	2004/01/24 10.33
		nitride) ceria silica (titanium adj		
		nitrido) (titania adi ministralia del	EPO; JPO;	
	1	nitride) (titanic adj nitride) titania	DERWENT;	
	1	titanium zirconia cermaic)	IBM_TDB	1
-	0	1 (01004100d040 DdpC141012C41COdC40) Sdille	USPĀT;	2004/07/24 16:36
		((silica adj nitride) (silicon adj	US-PGPUB;	
1		nitride) ceria silica (titanium adj	EPO; JPO;	
		nitride) (titanic adj nitride) titania		
]		titanium zirconia cermaic) same abrasive	DERWENT;	1
_	10	/orangilanaho2 with // il	IBM_TDB	1
_	16		USPAT;	2004/07/24 16:40
	[i	(silicon adj nitride) ceria silica	US-PGPUB;	
	1	(titanium adj nitride) (titanic adj	EPO; JPO;	
1		nitride) titania titanium zirconia	DERWENT;	
1		cermaic)) same abrasive	IBM TDB	l
_	25567	((hard abrasive) with ((silica adj		2004/07/04
	2330/	nitrido) (oiline edi :: :: :	USPAT;	2004/07/24 16:41
		nitride) (silicon adj nitride) ceria	US-PGPUB;	
	1	silica (titanium adj nitride) (titanic adj	EPO; JPO;	
		nitride) titania titanium zirconia	DERWENT;	
		cermaic))	IBM TDB	
_	8164	((hard abrasive) with ((silica adj	USPAT;	2004/07/24 16:41
		nitride) (silicon adj nitride) ceria		2004/07/24 16:41
	1	eilica (titanium add miturae) Ceria	US-PGPUB;	
		silica (titanium adj nitride) (titanic adj	EPO; JPO;	
		nitride) titania titanium zirconia	DERWENT;	1
		cermaic)) and alumina	IBM TDB	
_	5421	((abrasive) with ((silica adj nitride)	USPAT;	2004/07/24 16:42
,		(silicon adj nitride) ceria silica	US-PGPUB;	-001/0//24 10.42
ļ		(titanium adj nitride) (titanic adj		
	ļ ĺ	nitrido) titania titariam -:	EPO; JPO;	
		nitride) titania titanium zirconia	DERWENT;	[
	L	cermaic)) and alumina	IBM_TDB	
				L

	1 04			
-	2158	() = === ()	USPAT;	2004/07/24 16:42
	İ	(silicon adj nitride) ceria silica	US-PGPUB;	
		(titanium adj nitride) (titanic adj	EPO; JPO;	
		nitride) titania titanium zirconia	DERWENT;	
	ĺ	cermaic)) and alumina	IBM TDB	
-	725	((grind\$3) with ((silica adj nitride)	USPAT;	2004/07/24 16:42
		(silicon adj nitride) ceria silica	US-PGPUB;	
		(titanium adj nitride) (titanic adj	EPO; JPO;	
		nitride) titania titanium zirconia	DERWENT;	
		cermaic)) with alumina	IBM TDB	
-	0	((grind\$3) with ((silica adj nitride) and	USPAT	2004/07/24 16:43
		(silicon adj nitride) and ceria and silica	"""	2001/01/24 10:45
		and (titanium adj nitride) and (titanic		
		adj nitride) and titania and titanium and		
		zirconia and cermaic)) with alumina		
_	0		USPAT	2004/07/24 16:43
		nitride) and (silicon adj nitride) and	ODIAI	2004/07/24 10:43
		ceria and silica and (titanium adj		
		nitride) and (titanic adj nitride) and		
		titania and titanium and zirconia and	İ	
	ļ	cermaic)) with alumina		
_	395		USPAT	2004/07/26 09:37
		(silicon adj nitride) ceria silica	OSPAI	2004/07/26 09:37
		(titanium adj nitride) (titanic adj	}	<u> </u>
		nitride) titania titanium zirconia		
		cermaic)) with alumina		
_	772			
	1/2	(() Hours Highlight	USPAT	2004/07/26 09:37
	590	abrasive		
_	390	· · · · · · · · · · · · · · · · · ·	USPAT	2004/07/26 14:37
_		abrasive		
_	9	(((silica silicon) adj nitride) with	USPAT	2004/07/26 09:40
		abrasive) same (vapor adj deposition)		1
_	3	((ceria "CeO2") with abrasive) same (vapor	USPAT	2004/07/26 14:47
		adj deposition)		
_	6	(((titanic titanium) adj nitride) with	USPAT	2004/07/26 14:48
		abrasive) same (vapor adj deposition)		
_	25	((titania "TiO2") with abrasive) same	USPAT	2004/07/26 14:49
		(vapor adj deposition)		
-	25	(("titania" "TiO2") with abrasive) same	USPAT	2004/07/26 09:47
		(vapor adj deposition)		
_	10	((zirconia "ZrO2") with abrasive) same	USPAT	2004/07/26 14:49
		(vapor adj deposition)		
-	359	(ceria "CeO2" (cerium adj oxide)) same	USPAT	2004/07/26 13:56
		deposit\$3 same ("CVD" (vapor near3		
		deposition))		